

**Search Notes**

Application/Control No.

10/626,744

Examiner

ALI ALLAWI

Applicant(s)/Patent under  
Reexamination

YAMAMOTO ET AL.

Art Unit

2877

**SEARCHED**

Class	Subclass	Date	Examiner

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
Searched 250/461.1 radiant energy with ultraviolet source	11/10/2005	AA
Searched 356/446,447 for light reflection and diffusion	11/10/2005	AA
Consulted with primaries Smith and Coleman on scope and overview of the invention and key word search	11/10/2005	AA
Key word search included radiant energy, plasma source, euv, reflection, diffusion, wafer etching, semiconductor, photoresist	11/10/2005	AA
deposition and deposition measurement and sensing was also searched, see east history for details	11/10/2005	AA